

L Numb r	Hits	Search T xt	DB	Time stamp
-	680	(345/30,55,84).ccls.	USPAT; US-PGPUB	2003/02/13 18:12
-	3	("5061049" "5583688" "6147790").pn.	USPAT; US-PGPUB	2003/02/13 18:16
-	2691	(mems r microelectr mechanical or (micr adj electro adj mechanical)) and (mirror or reflect\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:19
-	3369	(mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:20
-	0	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3)) and (semiconduct\$3 with substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:20
-	734	((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3)) and (semiconduct\$3 with substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:20
-	120	((((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3)) and (semiconduct\$3 with substrate)) and torsion\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:21
-	3	(((((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3)) and (semiconduct\$3 with substrate)) and torsion\$2) and (switch\$3 same voltage)) and (memory same stor\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/13 18:21
-	1711	(359/223,224,290-292,298).ccls. (345/85).ccls.	USPAT; US-PGPUB	2003/02/13 18:25
-	29	(((((mems or microelectromechanical or (micro adj electro adj mechanical)) and (mirror or reflect\$3 or deflect\$3)) and (semiconduct\$3 with substrate)) and torsion\$2) and (switch\$3 same voltage)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:28
-	6262	(mems or microelectromechanical or (micro adj electro adj mechanical))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:44
-	1128	((mems or microelectromechanical or (micro adj electr adj m chanical)) ) and semiconduct\$3 n ar5 substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:43

-	114	(((mems or microelectromechanical or (micro adj l ctro adj m chanical)) ) and semiconduct\$3 n ar5 substrate) and torsion\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:29
-	38	(((m ms or micro lectrom chanical or (micr adj el ctro adj mechanical)) ) and semiconduct\$3 near5 substrate) and torsion\$2) and (driv\$3 with voltage)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:30
-	12	((((mems or microelectromechanical or (micro adj electro adj mechanical)) ) and semiconduct\$3 near5 substrate) and torsion\$2) and (driv\$3 with voltage)) and memory	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:35
-	23	((((mems or microelectromechanical or (micro adj electro adj mechanical)) ) and semiconduct\$3 near5 substrate) and torsion\$2) and memory) not ((((((mems or microelectromechanical or (micro adj electro adj mechanical)) ) and semiconduct\$3 near5 substrate) and torsion\$2) and (driv\$3 with voltage)) and memory)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 12:35
-	115	((mems or microelectromechanical or (micro adj electro adj mechanical)) ) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:04
-	6262	(mems or microelectromechanical or (micro adj electro adj mechanical))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:03
-	115	((mems or microelectromechanical or (micro adj electro adj mechanical)) ) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:39
-	7	(US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.	USPAT; US-PGPUB	2003/02/14 13:38
-	1	US-20020076138-A1.DID. and ((mems or microelectromechanical or (micro adj electro adj mechanical)) )	USPAT; US-PGPUB	2003/02/14 13:38
-	7	((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ r US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems r micr electr mechanical r (micr adj electro adj mechanical)) )	USPAT; US-PGPUB	2003/02/14 13:38

-	3	(((US-5905571-\$ r US-6518609-\$ r US-6473361-\$ or US-6312134-\$ r US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or micr electr m chanical r (micr adj l ctro adj m chanical)) )) and (((m ms or micr electromechanical or (micro adj electro adj mechanical)) ) and semiconduct\$3 near5 substrate)	USPAT; US-PGPUB	2003/02/14 13:38
-	4	(((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and torsion\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:40
-	3580	(micro adj mirror) or micromirror	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:40
-	3073	((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 14:56
-	1711	(((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:42
-	25	(((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:46
-	173	(((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:43
-	30	(((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (memory same capacitor\$1)) (((micro adj mirror) or micromirror) not ((mems or micro lectr mechanical r (micr adj electro adj mechanical)) )) and (actuat\$3 or torsi n\$2 r driv\$3)) and (m m ry same capacit r\$1))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:44

-	67	(((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. r (US-20020149834-\$).did.) and ((mems r microelectr mechanical r (micr adj electr adj mechanical)) )) and t rsi n\$2) (((((micr adj mirror) or micromirr r) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:45
-	63	(((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:45
-	67	(((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:45
-	4025	"67" and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 14:19
-	10	(((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and torsion\$2) (((((micro adj mirror) or micromirror) not ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (actuat\$3 or torsion\$2 or driv\$3)) and semiconduct\$3 near5 substrate) and torsion\$2) (((((micro adj mirr r) or micr mirr r) n t ((m ms r micr electromechanical or (mi r adj lectr adj mechanical)) )) and (actuat\$3 r t rsi n\$2 or driv\$3)) and s mic nduct\$3 near5 substrate) and t rsi n\$2)) and (m m ry same capacit r\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:52

-	2	6266178.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 13:52
-	5	(US-6473361-\$ r US-6242989-\$ r US-5867302-\$ or US-6046840-\$ r US-6266178-\$).did.	USPAT	2003/02/14 14:19
-	5	((US-6473361-\$ or US-6242989-\$ or US-5867302-\$ or US-6046840-\$ or US-6266178-\$).did.) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 16:08
-	9335	((mems or microelectromechanical or (micro adj electro adj mechanical)) ) ((micro adj mirror) or micromirror)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 16:08
-	55	((((mems or microelectromechanical or (micro adj electro adj mechanical)) ) ((micro adj mirror) or micromirror)) and ((memory adj cell) with driv\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 16:10
-	67	((((mems or microelectromechanical or (micro adj electro adj mechanical)) ) ((micro adj mirror) or micromirror)) and ((memory adj cell\$1) with driv\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 16:10
-	5	((((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (memory same capacitor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 11:35
-	3	(((((US-5905571-\$ or US-6518609-\$ or US-6473361-\$ or US-6312134-\$ or US-6242989-\$ or US-5867302-\$).did. or (US-20020149834-\$).did.) and ((mems or microelectromechanical or (micro adj electro adj mechanical)) )) and (memory same capacitor\$1)) and (memory adj cell\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/14 17:15
-	9370	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)) )	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 14:56
-	251	((((micro adj mirror) or micromirror) or ((mems or micr el ctrom chani al r (micr adj el ctr adj mechanical)) )) and (m mory adj2 cell)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 15:09

-	12	((micro adj mirror) or micromirror) or ((mems r micro l ctmom chanical or (micro adj el ctr adj m chanical)) ) and ((memory adj2 cell) same capacitor\$1 same transistor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 14:57
-	12	((micr adj mirror) r micromirr r) r ((mems or micr el ctr mechanical r (micro adj electro adj mechanical)) ) and (memory adj2 cell)) and ((memory adj2 cell) same capacitor\$1 same transistor\$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/19 14:57
-	44	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)) ) and (memory adj2 cell)) and ground	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:25
-	5	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)) ) and (memory adj2 cell)) and (ground same reset\$4)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:52
-	17	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)))) and (pass adj transistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:53
-	11	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)))) and ((pass adj transistor) same capacitor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 12:58
-	2	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)))) and ((pass adj transistor) same capacitor same gate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:00
-	64	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)))) and ((transistor) same capacitor same gate) and ground\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:00
-	37	((micro adj mirror) or micromirror) or ((mems or microelectromechanical or (micro adj electro adj mechanical)))) and ((transistor) same capacitor same gate) and (transistor same ground\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:26
-	2	5285407.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/02/20 13:26